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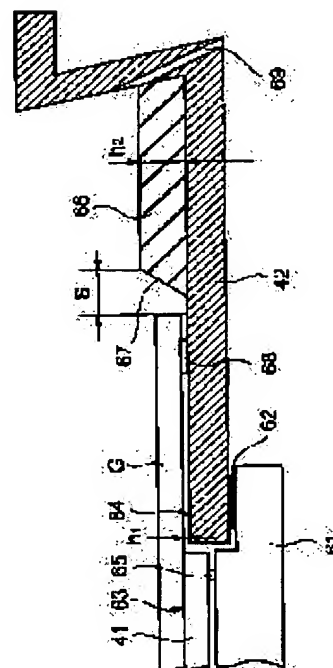
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(54) LIQUID SUPPLYING APPARATUS

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a liquid supplying apparatus capable of avoiding occurrence of defects such as cracking of a substrate, preventing mist-like stain formation in the rear face of a substrate and preventing a supplied liquid from flowing around to the rear face of the substrate.

SOLUTION: The floor face 64 of a rotation cup 42 is lowered than a substrate holding face 63 of a spin chuck 41 by 0.2-0.4 mm and a plate 66 is installed so as to face to the outer circumference along the outer circumference of a substrate G, so that stain formation in the rear face of the substrate G owing to mist or the like can be prevented. Moreover, a resist solution or the like is prevented from entering in the gap between them. Further, the substrate G is kept from contact with the floor face 54 when the spin chuck 41 is moved down, so that the substrate is protected from defects such as cracking or the like.



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